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** CONTINUING DATA *****
 This application is a CIP of PCT/JP02/04594 05/13/2002

** FOREIGN APPLICATIONS *****
 JAPAN JP2001-172645 06/07/2001
 JAPAN JP2002-353141 12/04/2002

IF REQUIRED, FOREIGN FILING LICENSE GRANTED
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Foreign Priority claimed 35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> Met after Allowance	STATE OR COUNTRY JAPAN	SHEETS DRAWING 11	TOTAL CLAIMS 27	INDEPENDENT CLAIMS 7
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Verified and Acknowledged

Examiner's Signature: *[Signature]* Initials: *[Initials]*

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TITLE
 Electron beam exposure apparatus, electron beam exposing method, semiconductor element manufacturing method, and pattern error detection method

FILING FEE	FEES: Authority has been given in Paper	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of
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